# **Photonic Nanostructures for Solar Cell Light Trapping with Colloidal Lithography**

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Photonic structures with wavelength-scale dimensions are highly promising for light trapping strategies applied to thin film photovoltaic (PV) devices. When applied on the front transparent contact of solar cells, optimally-shaped highindex dielectric structures can act as high-performing broadband anti-reflectors and scattering elements boosting the light absorption of the cell material along its photo-response spectrum.

Exact electromagnetic computational optimization shave provided the best parameters of the structures and indicated that TiO<sub>2</sub> is one of the most favorable materials. Therefore, in this work, we present an innovative nanosphere lithography method that allows the precise engineering of TiO, wavelength-sized features with the distinct shapes and sizes appropriate for efficient light trapping in different thin film PV devices. This is a simple, low-cost and scalable approach consisting in 4 main steps.



a-Si/TiO<sub>2</sub> NS





### FDTD computed absorptance distributions

Nanostructures fabrication steps:

ES, G AND

A) Self-assembly technique: Deposition of a Polystyrene

## **Optical Measurements** and simulations



#### Conclusions

- microspheres (1-2 µm diameter) monolayer by Langmuir-Blodgett
- B) O<sub>2</sub> Dry Etching treatment: shaping of the spheres and increase of their inter-particle spacing (s)
- C) RF magnetron Sputtering: infiltration of the high index  $TiO_2$ material

D)Lift-off: removal of the spheroids sonication in a Toluene Bath

We developed a colloidal lithography (CL) methodology to fabricate  $TiO_2$ based light trapping structures, with sizes within the wave-optical regime, to be applied on the front surface of thin film solar cells. Such nanostructured antireflection coatings provide the cells with an optical enhancement estimated to yield a promising increment of 58.7% and 27.3% (relative to an unpatterned a-Si:H cell and a cell patterned with an ARC, respectively) in the photocurrent density supplied by the cell.

